

**AMENDMENTS TO THE SPECIFICATION:**

Please replace paragraph beginning on page 9, line 15 with the following amended paragraph:

It is important to note that inasmuch as the present invention utilizes RF energy to create a plasma and to process materials, electrically conductive enclosure **11** does not necessarily need to be grounded. In some circumstances it may be desirable to have electrically conductive enclosure **11** floating and apply RF energy **15** at some predetermined phase, which can differ by as much as 180°, with respect to RF energy **16** applied to electrode **13**, to enhance the effectiveness of the processing. In this situation, a protective, grounded casing **14**, shown by dashed lines in Figure 1, would enclose the invention for safety reasons. An appropriate frequency for the RF energy used in the present invention is 13.56 Megahertz (MHz), however other RF frequencies might also prove useful.